

Application/Control No.	Applicant(s)/Patent under Reexamination	
10/617,172	KIM ET AL.	
Examiner	Art Unit	
Tianjie Chen	2627	

SEARCHED					
Class	Subclass	Date	Examiner		
Updated		6/15/2006	TJ		
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INTERFERENCE SEARCHED					
Class	Subclass	Date	Examiner		
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SEARCH NOTES (INCLUDING SEARCH STRATEGY)				
	DATE	EXMR		
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